

MICRO-ELECTROMECHANICAL DEVICE

ABSTRACT

An electromechanical device (201) includes a support
5 structure (210) formed by attaching inner surfaces of
second and third substrates (220a-b) to a first substrate
(230). The support structure (210) includes at least one
cavity (250) between the second and third substrates
(220a-b). An electromechanical active element (260a-b),
10 such as a piezoelectric element, is provided on an outer
surface of at least one of the second or third layers
(220a-b).

FIG 2



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